

ABSTRACT

5 A plurality of elements such as a resistor (10),
capacitor (20), and coil (30) and switches 41 to 44 for
connecting these elements are formed integrally on a
substrate 1 and the elements are made freely connectable
to form a MEMS array. The switches 41 to 44 used may be
transistor switches or mechanical switches. It is
possible to produce a MEMS device by replacing the on/off
10 states of the switches 41 to 44 of the MEMS array with
short-circuited/open states of the interconnects.